AMENDMENTS TO THE SPECIFICATION:

- Page 1: Before paragraph [0001], please insert the
 following:
- --This application claims the benefit of U.S. Provisional Patent Application Serial No. 60/425,805 filed November 13, 2002.--
- Page 4, replace the paragraph at lines 18-19 with the
 following amended paragraph:
- Fig. 14 is an exploded view showing Figs. 14a and 14b are exploded views showing a third embodiment of the present invention;
- Page 19, Replace paragraph [0082] with the following amended
 paragraph:

Next, the Figs. 14 and 15 Figs. 14a, 14b and 15 explain as to the embodiment using the electrostatic force for the driving section. A mirror portion 302 is formed at the center portion of an upper plate 301, on which a silicon substrate is formed with the etching process, and the surface of the mirror portion 302 is applied with gold coatings, thereby forming a mirror surface 302a with high reflectance. A projection 302b is formed on the both sides thereof, and a hole 302c is formed at the center thereof.

Moreover, an S shaped spring portion 303 is thinly formed in the outer side of the projection 302b, and the fixing portion 301a

and the projection 302b are connected by the spring portion 303. A silicon substrate is formed on a lower plate 304 with the etching process, a central portion thereof is formed to concave shape, and two electrode portion 306a and 306b are formed on the bottom thereof.